Deposition System Technology for Wide Bandgap Materials

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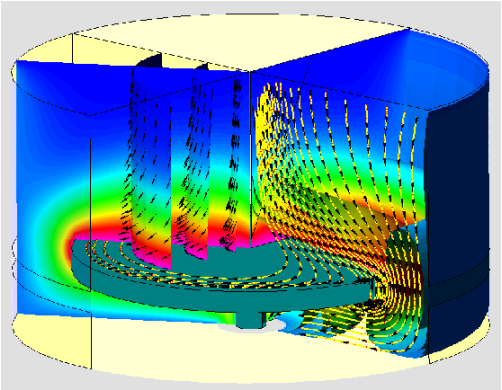
Deposition System Technology for Wide Bandgap Materials

Chemical vapor Deposition (CVD) and Metal Organic Chemical vapor Deposition (MOCVD).

Thin Films and Bulk Materials

Hardware and Process Technology is Available for Wide Bandgap Materials

- Group III-Nitrides
- SiC
- ZnO
- Diamond
- Graphene



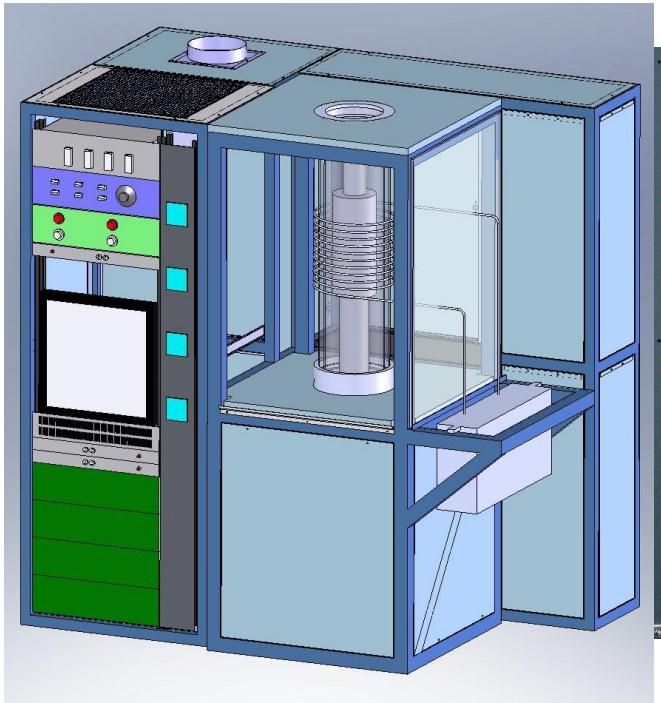
Group III-Nitrides; GaN, AlGaN, InGaN

Thin Films / Bulk Materials

Metal Organic Sources / Metallic Sources

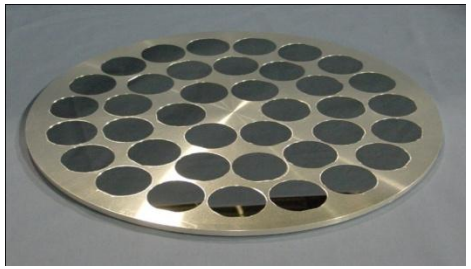
Silicon Carbide

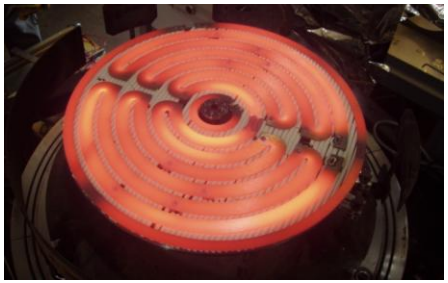
Thin Film and Bulk Crystal Growth

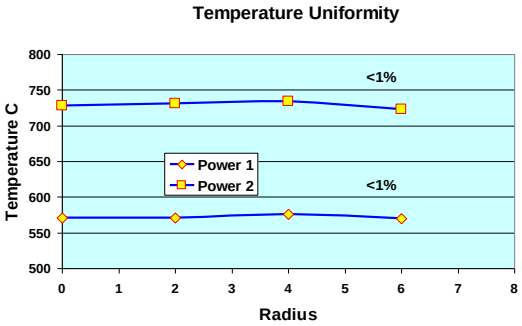


Zinc Oxide

n-Type ZnO, *p*-Type ZnO, Transparent Conductive Oxides



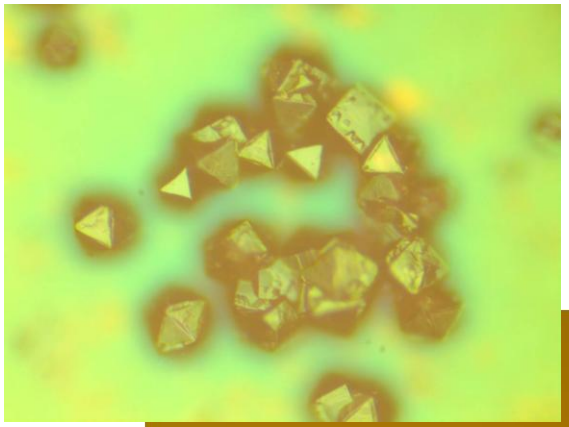


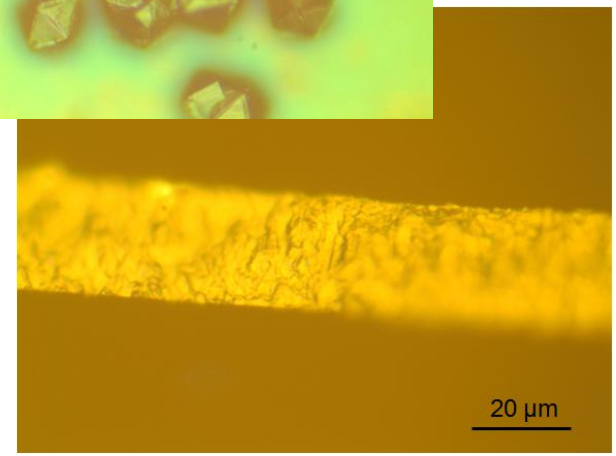


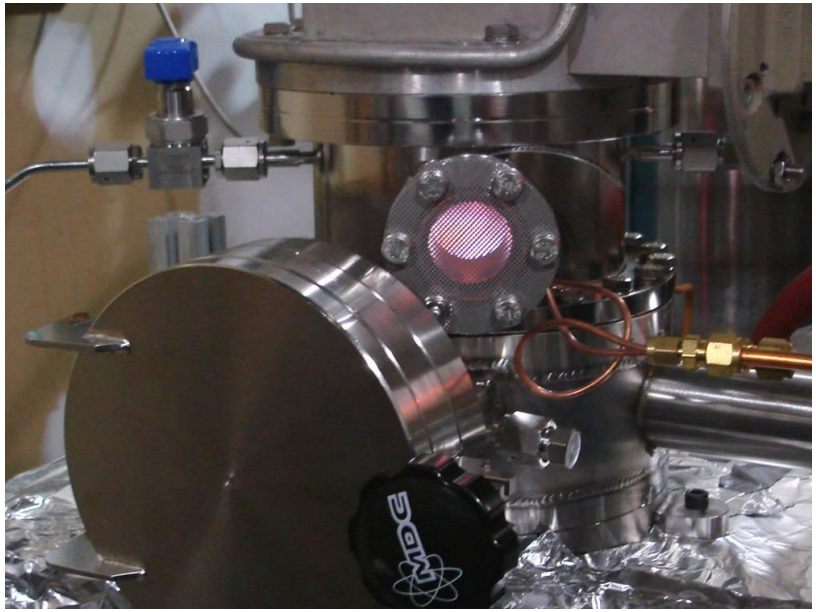
Diamond

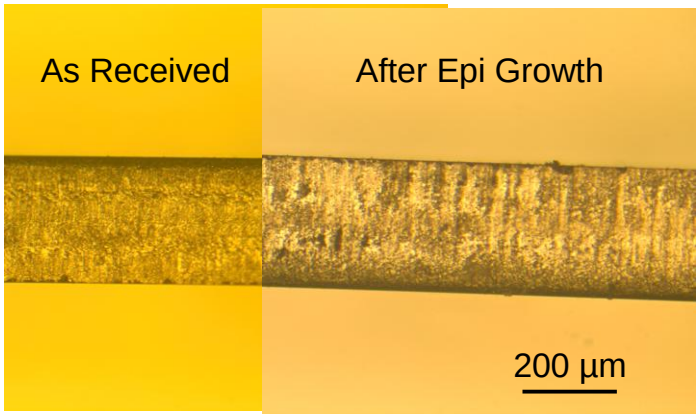
Microwave Plasma CVD

- Polycrystalline Diamond
- Homoepitaxial Diamond

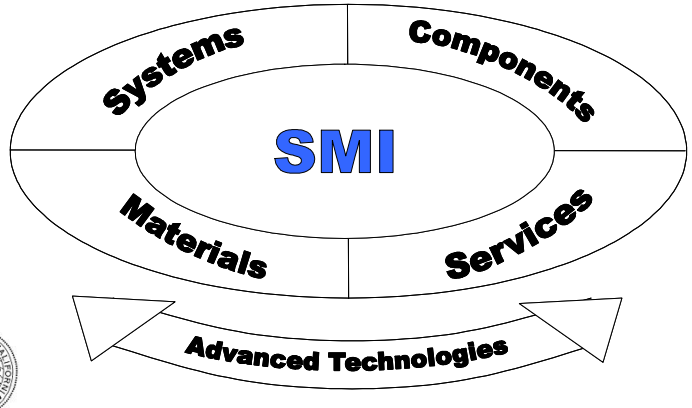


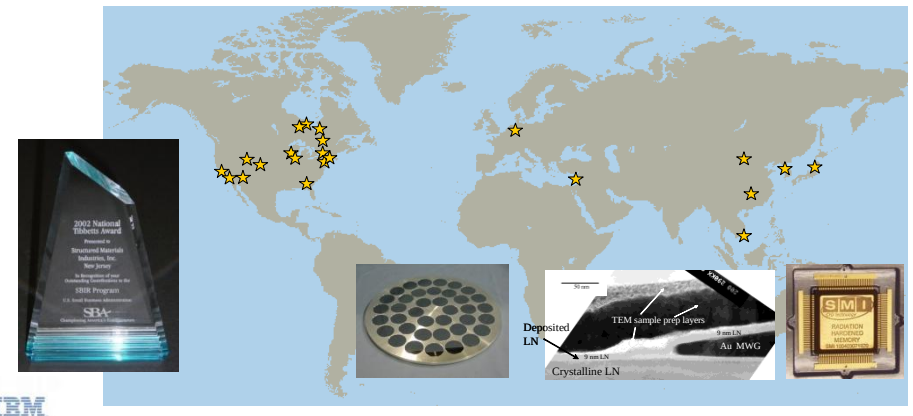






SMI Welcomes Development Partnerships for Wide Bandgap Materials





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